



PATENT

IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

In re the application of)	
)	Atty. Docket No. LAM2P222A
SALDANA et al.)	
)	
Application No. 09/748,708)	Examiner: G. B. M. Nguyen
)	
Filed: December 22, 2000)	
)	Group Art Unit: 3723
For: POLISHING APPARATUS AND METHODS)	
HAVING HIGH PROCESSING WORKLOAD)	
FOR CONTROLLING POLISHING PRESSURE)	Date: September 10, 2002
<u>APPLIED BY POLISHING HEAD</u>)	

CERTIFICATE OF MAILING

I hereby certify that this correspondence is being deposited with the United States Postal Service as First Class Mail in an envelope addressed to: Commissioner for Patents, Washington, DC 20231 on September 10, 2002.

Signed: _____

Kay Harlow

AMENDMENT AND RESPONSE

Assistant Commissioner for Patents
Washington, D.C. 20231

Sir:

In response to the Office Action mailed June 20, 2002, please amend the captioned Application as follows and consider the following remarks.

IN THE SPECIFICATION

Please amend the paragraph starting at page 19, line 19 to read as follows:

The processing of the data representing the forces, and of the polishing head positions with respect to the resulting contact areas, may be performed by a central processor, or separately by a force controller, according to operational criteria in a processor guideline. The processor guideline relates to the level of processing workload, and may be used to determine whether the central processor alone, or the processor in conjunction with the separate force controller, is suitable for processing